



MAGPULS MP 2 - L1 Series **BIPOLAR Pulse Power Supply LAB 100 kHz**









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World Wide Sales & Support through Dynamic Partners



Highest flexibilty

Supreme performance for Single Magnetron sputtering processes, Plasma Nitriting Processes & Bias application.

MAGPULS MP2-L1 Series Bi-Polar Pulse Power Supplies, specially designed for R&D and Laboratory usage, are suitable for operating with single magnetron for non-reactive sputtering deposition on substrates such as metals. Individual operating modes and enhanced ARCmanagement allows MP2-L1 Pulse Power Supplies to operate effectively in achieving superior quality deposition. Typical applications of MP2-L1 are production of Hard Coatings, Plasma Nitriding & Biasing.

MP2-L1 Units are designed to operate in the frequency range of 1 to 100 kHz and can deliver power up to 3 kw with pulse current up to 35 A (peak current). Higher frequency / current / power models are available.

MP2-L1 Series PS is made up of mainly two units. The first unit is the DC power supply, which provides DC power into the big capacitor bank of the pulse unit. The second unit is the Pulsar, an intelligent circuitry, which is equipped with highly sophisticated ARC management capability.

Duty Cycle can be adjusted to achieve higher target utilisation & for better optimisation of the processes. Enhanced ARC management provides best coating results without process interruptions. Optionally, there is an external Optical Input Interface for controlling of the pulse PS externally. It also has an Optical Output Interface for triggering or synchronization of other pulse power supplies of MP1 or MP2 series.

VOLTAGE PULSING - Descrete Advantage

MAGPULS Pulse Power Supplies are designed on Voltage Pulsing Technology (VPT). Unlike in Current Pulsing Technology, users can set the amplitude of the Pulse (voltage) in VPT Pulsars. This provides a very tight control on the process. Stable plasma condition is easily achievable at low pulsing frequencies, well below 100kHz. Pulsing current is in correlation with the plasma impedance & temperature stress on the coating products can be controlled very effectively.

Features and Benefits

Adjustable Pulse Parameters & Frequency		Universal Application Range One power supply
7 Different Output operating modes	>	Optimal adjustment of process for better process stability
DC+, DC-, Uni-Polar+, Uni Polar +, Bipolar Pulse, Programmable Pulse Train, Synchronization	>	Better control of power optimized target utilization
Enhanced Effective ARC management	>	Quick Arc-suppression. Lowest Arc-energy. Best results

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	MP1-35 / 1 kW	MP1-35 / 2 kW	MP1-35 / 3 kW	
OUT PUT				
Voltage		0 - 1000 V		
Current	0 - 1.4 A DC 0 - 35 A Pulse	0 - 2.8 A DC 0 - 35 A Pulse	0 - 5.3 A DC 0 - 35 A Pulse	
Power	0 - 1 kW DC	0 - 2 kW DC	0 - 3 kW DC	
Pulse Frequency	DC or 0.05 Hz - 100 kHz			
Max. Frequency with Max. Pulse Current	100 kHZ at 10 A 25 kHZ at 35 A			
Pulse Time Settings Ton / Toff	5.0 μs up to 100 sec / 5.0 μs up to 100 sec			
Duty Cycle		0.005 % to 100 %		
Pulse wave form	DC+ Unipolar pulse Programmable Pulse Train			
IN PUT				
Max. Voltage	0 - 1000 V			
Max. Current	0 - 1.4 A DC	0 - 2.8 A DC	0 - 5.3 A DC	
Max. Power	0 - 1 kW DC	0 - 2 kW DC	0 - 3 kW DC	
Mains Supply		1 Φ 230 V AC 50/60 Hz		
ARC-MANAGEMENT		0 - 35 A peak		
ARC-Detection Time	0 - 35 A peak < 200 ns			
Off Time after ARC-Detection	< 200 ns			
ARC-Recovery Time	≥ 100 μs			
di/dt Dynamic Change	Var. di/dt threshold: 0 A/μs up to 2000 A/μs			
Voltage Drop ΔU	Var. U threshold: 0 % up to 100 % Upc (Option)			
U x I - Cross Detection	Var. U threshold: 0 V up to 1000 V Var. I threshold: 0.1 x max. I _{peak} up to 1 x max I _{peak} (Option)			
INTERFACE				
Analog	1 (up to 3) 15 pin-Su	b-D for controlling externa	DC power supplies	
Digital	15 pin Sub-D user Interface with floating potential contactors			
RS 232	9 pin Sub-D			
Ethernet	RJ 45			
Profibus	9 pin Sub-D (Option)			
TEMP MANAGEMENT				
Cooling System	Air cooling			
Cooling Temperatur	Max. 35°C			

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	MP1-35 / 1 kW	MP1-35 / 2 kW	MP1-35 / 3 kW	
ENV CONDITION				
Ambient Temperature	+ 5 °C up to + 35 °C			
Max. Humidity	80 % non condensing			
Max. Operation Altitude	1500 m above sea level			
MECHANICAL DATA				
Construction	19"-Rack 5 HU			
Dimensions H x W x D	222.25 mm x 483 mm x 650 mm			
Weight	20 kg	24 kg	26 kg	
DISPLAY & CONTROLS				
Display	Graphic color display			
LED Display	Power, OK, Start / Stop			
Controls	Graphical menu via function keys, arrow keys and continous rotating knob			
SUITABILITY				
Application	Hard Coating on Tools & Bits and BIAS application			
Process	PVD, Plasma Nitriding, Pulse Plasma, Reactive Sputtering, Dual & Single Magnetron Sputtering			
Material	Metals			

Please contact us for information on higher capacity models & other variants



OUT PUT Waveforms











